

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Ning Docket No.: 01P7422 US
Serial No.: 09/854,760 Art Unit: 1756
Filed: May 14, 2001 Examiner: Vinh, Lan
Title: Design Lithography Alignment and Overlay Measurement Marks on CMP
Finished Damascene Surface

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

RESPONSE UNDER 37 CFR 1.111

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's Office Action mailed on June 10, 2003. They are respectfully submitted as a fully and complete response to that Office Action. Favorable consideration of the above-referenced patent application is respectfully requested.

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